

2871
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Inventors: Apostolos Voutsas

Serial No: 09/893,866

Filed: June 28, 2001

Title: METHOD FOR FORMING
SILICON FILMS WITH TRACE
IMPURITIES

PATENT APPLICATION

Attorney Docket No.
SLA0592

Group Art Unit: 2871

Examiner:

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this correspondence is being deposited
in the United States Postal Service with sufficient postage as first
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David C. Ripma, 27,672
Signature Date: 2/25/02

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**TRANSMITTAL OF SUPPLEMENTAL
DECLARATION UNDER 37 C.F.R. §1.67(a)**

Hon. Commissioner for Patents
Washington, D.C. 20231

Sir:

This correspondence transmits an accompanying Supplemental Declaration in the above-identified patent application. The Supplemental Declaration includes language inadvertently omitted from the originally-filed Declaration stating that the person making the declaration has reviewed and understands the contents of the specification, including the claims, as amended by

any amendment specifically referred to in the declaration, and acknowledges the duty to disclose information which is material to the examination of the application in accordance with 37 C.F.R. §1.56.

Please enter this Supplemental Declaration in the application file.

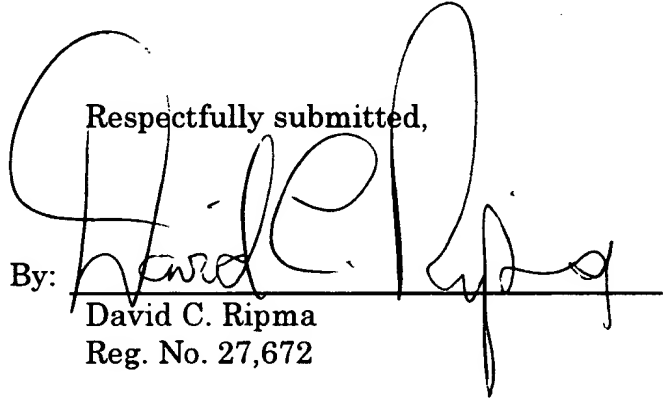
The Commissioner is hereby authorized to charge any fees associated with this communication to Deposit Account No. 19-1457. A duplicate copy of this authorization is enclosed.

Date:

Feb 25, 2002

By:

Respectfully submitted,


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